

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Tetsuo SHIMOMURA et al.
App. No : 10/598,717
Filed : September 8, 2006
For : POLISHING PAD AND
SEMICONDUCTOR DEVICE
MANUFACTURING METHOD
Examiner : Alvin J. Grant
Art Unit : 3723
Conf No. : 9262

AMENDMENT ACCOMPANYING RCE

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed November 12, 2008, please reconsider the present application in light of the following amendments and comments

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.